

Isolating the TEM instrumental function for electron PDF (ePDF)

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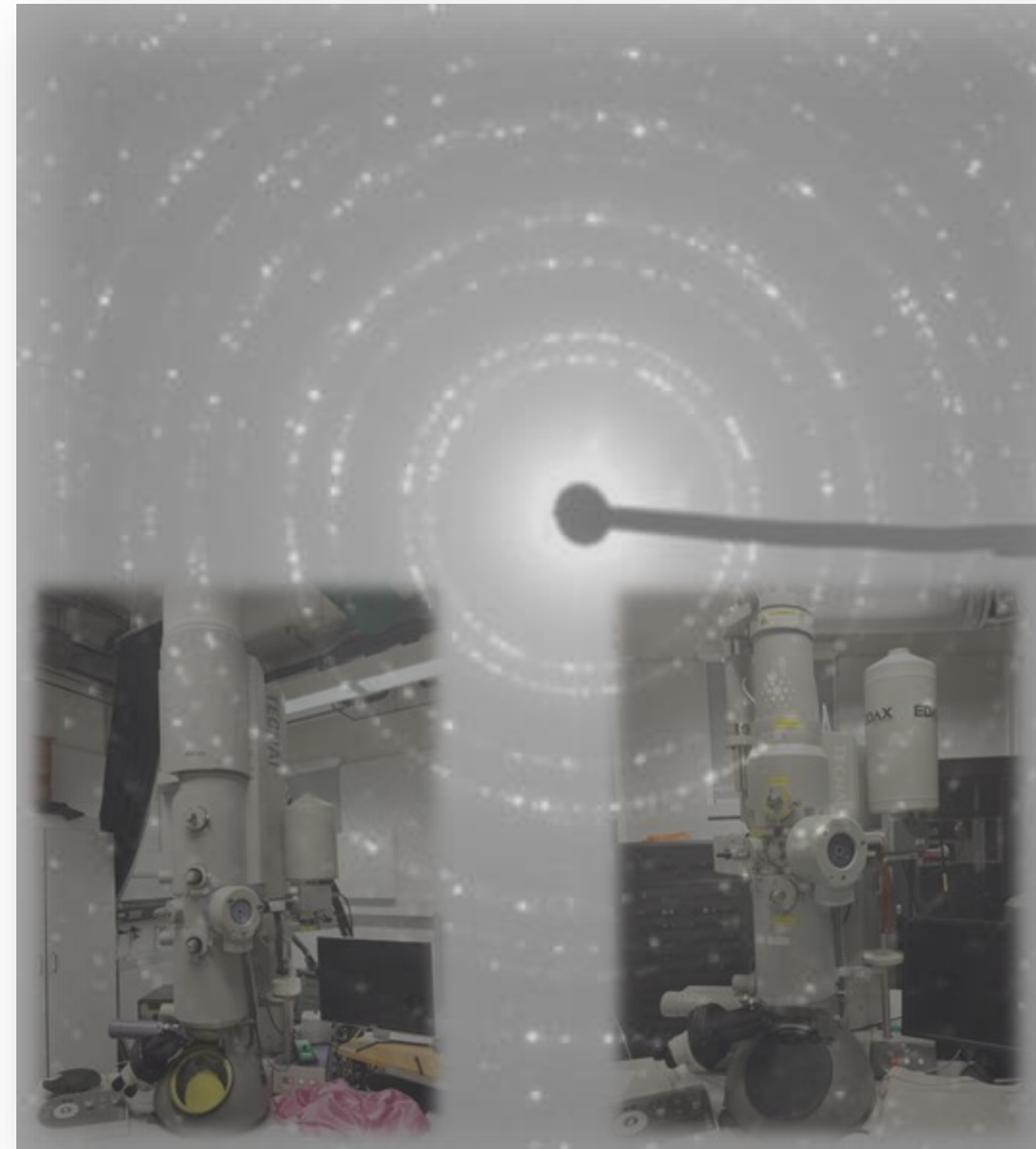
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Brazilian Nanotechnology
National Laboratory



CNPq
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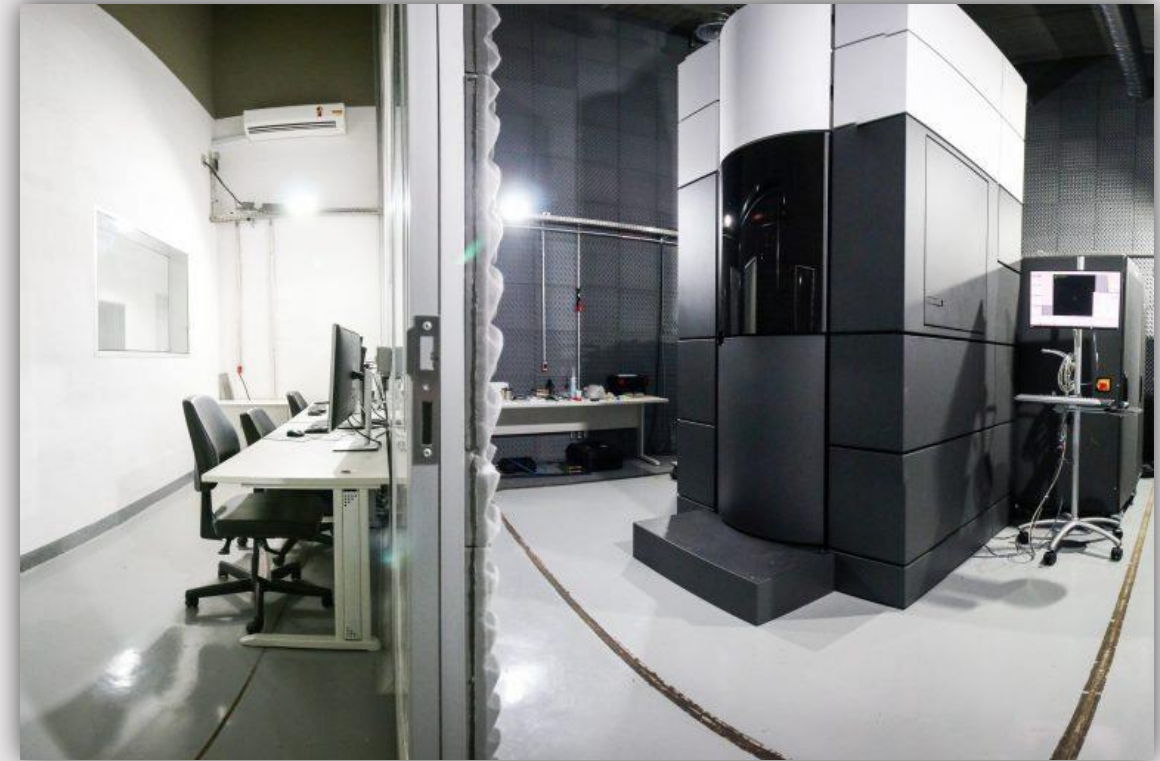
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Motivation



X-ray and Neutron PDF: Reliable, quantitative and well-developed.



Electron PDF: Emergent

Advantages: Spatial resolution, elemental contrast, sample amount.

Challenges: Electron form factors, dynamic scattering, instrument function unknown.

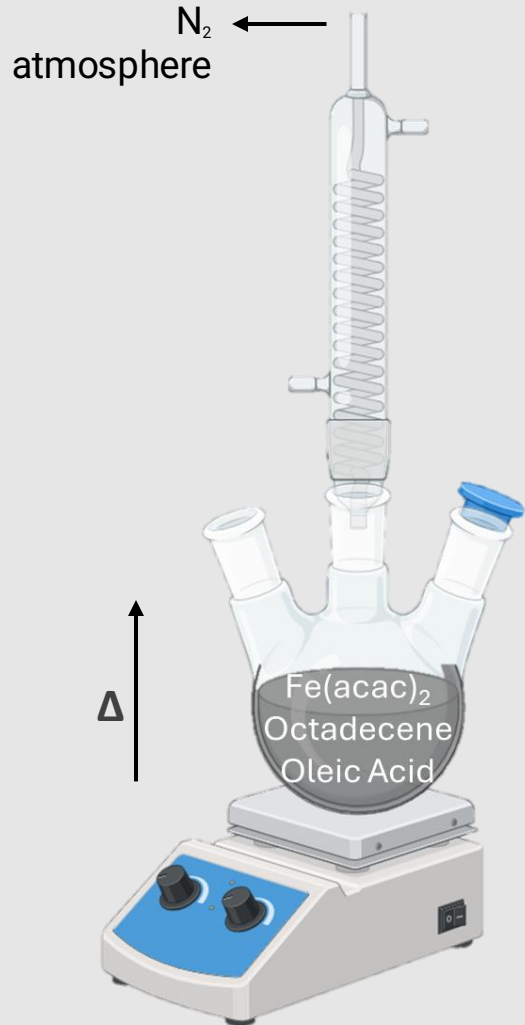
Outline

Transmission electron microscope instrument contribution to electron diffraction modelled by a pseudo-Voigt convolution to a Debye Scattering calculation for monodisperse particles.

- Synthesis and grid preparation
- TEM illumination and setup
- Data processing
- Modelling and Refinement

Synthesis of Fe_3O_4 particles

① Synthesis



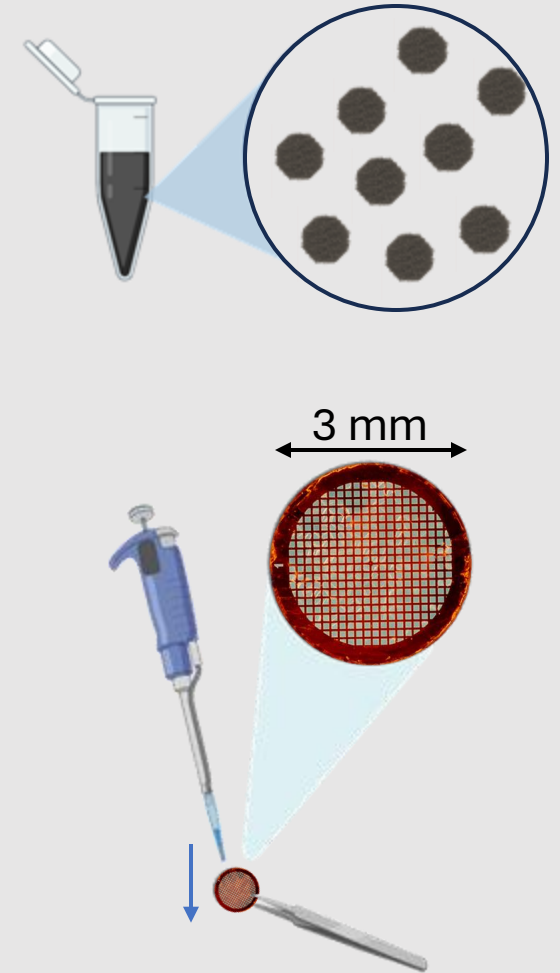
② Centrifuging



③ Redispersión

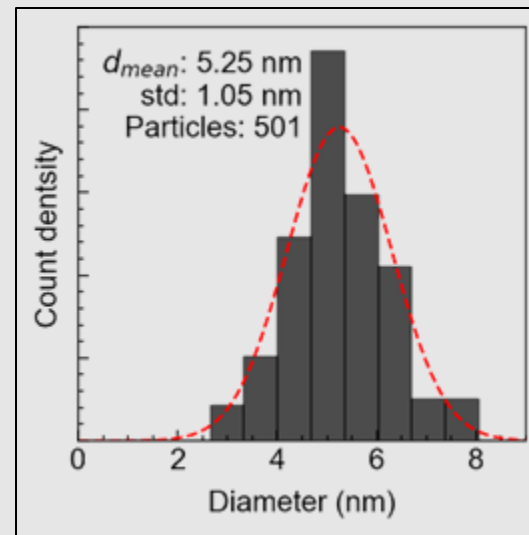
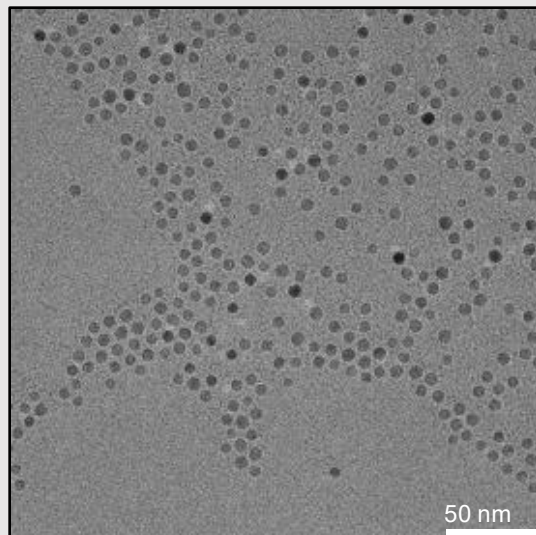
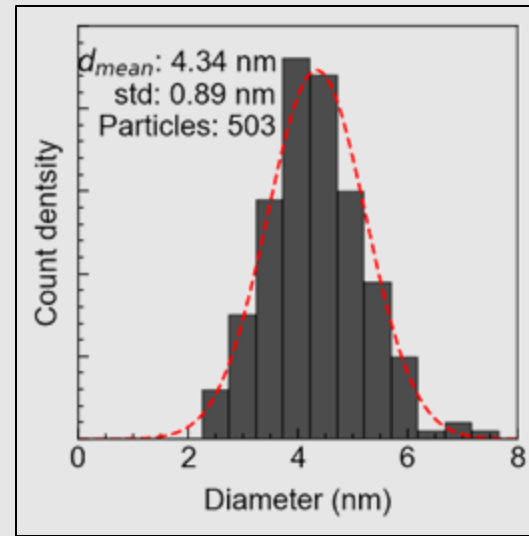
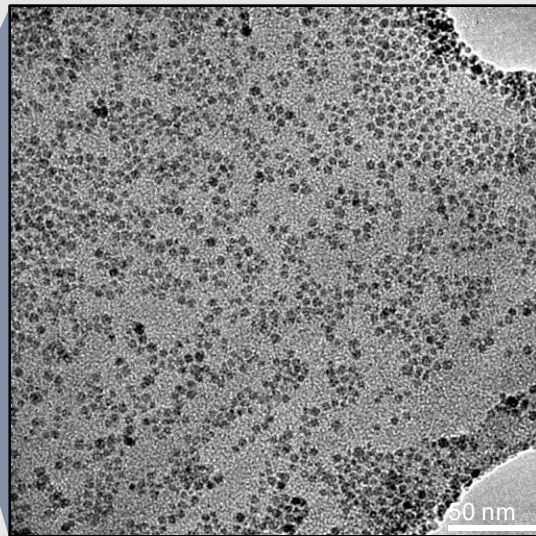


④ Vertical drop casting

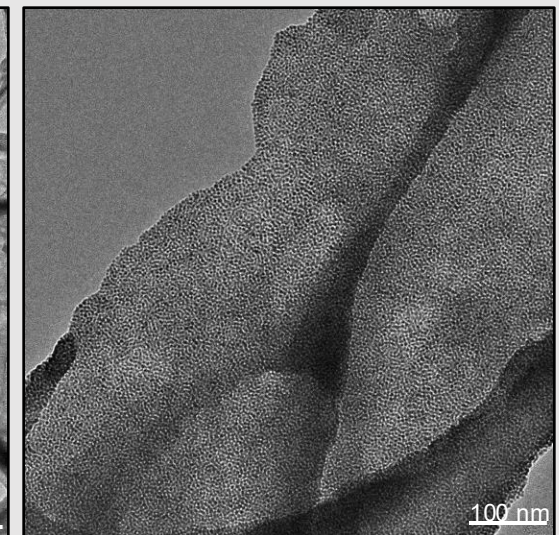
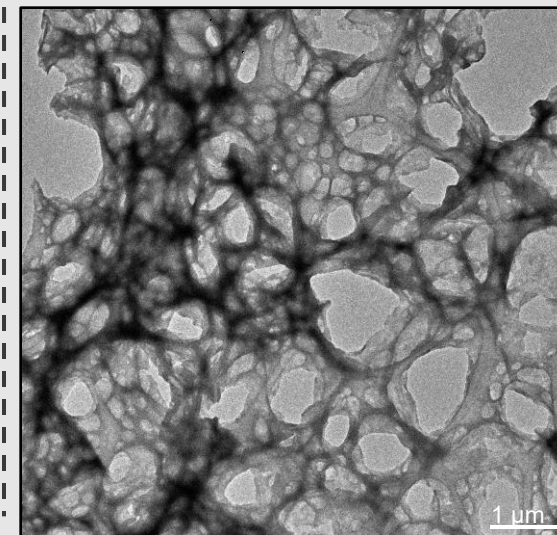
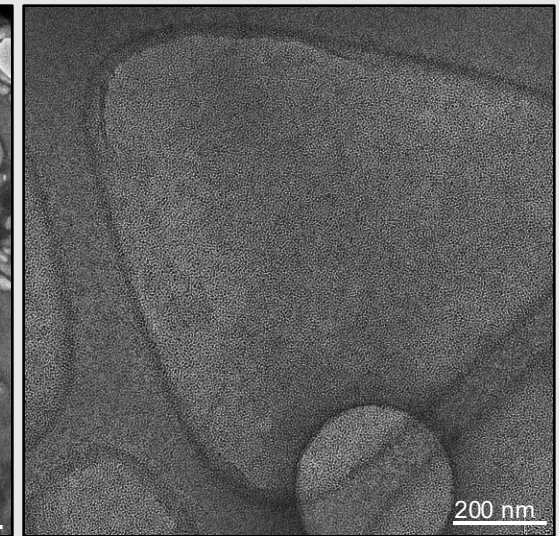
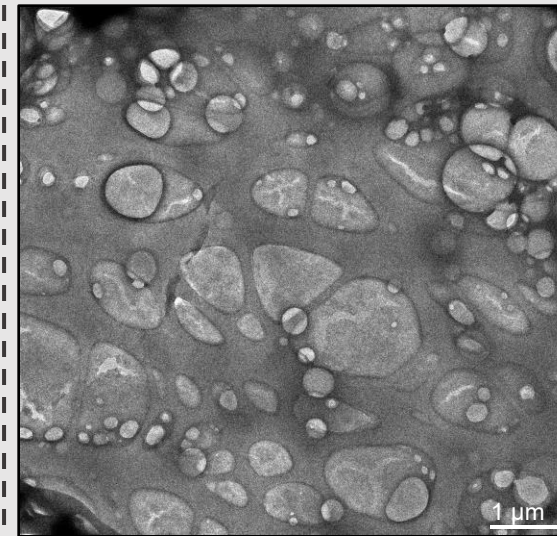


Monophasic Fe_3O_4 Nanoparticles

Narrow Distribution



Thin Film Formation



TEMs & Detectors

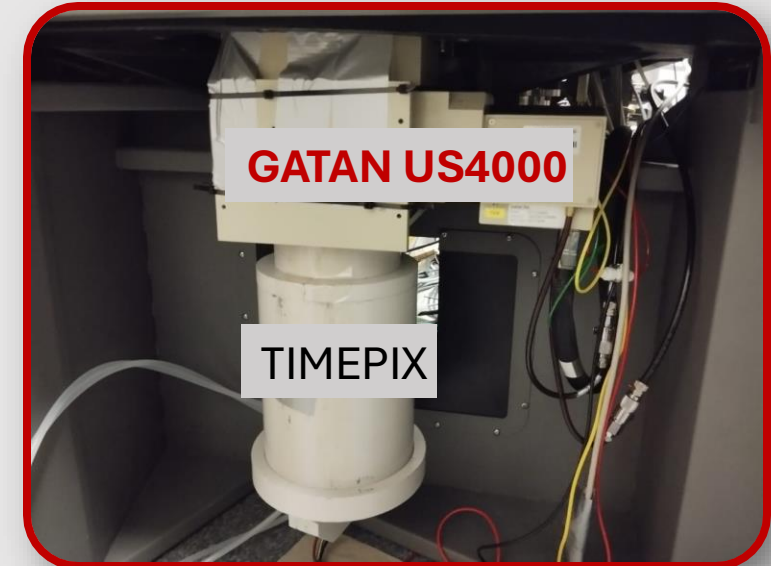
FEI TECNAI F30



FEI TECNAI SPIRIT



GATAN US4000



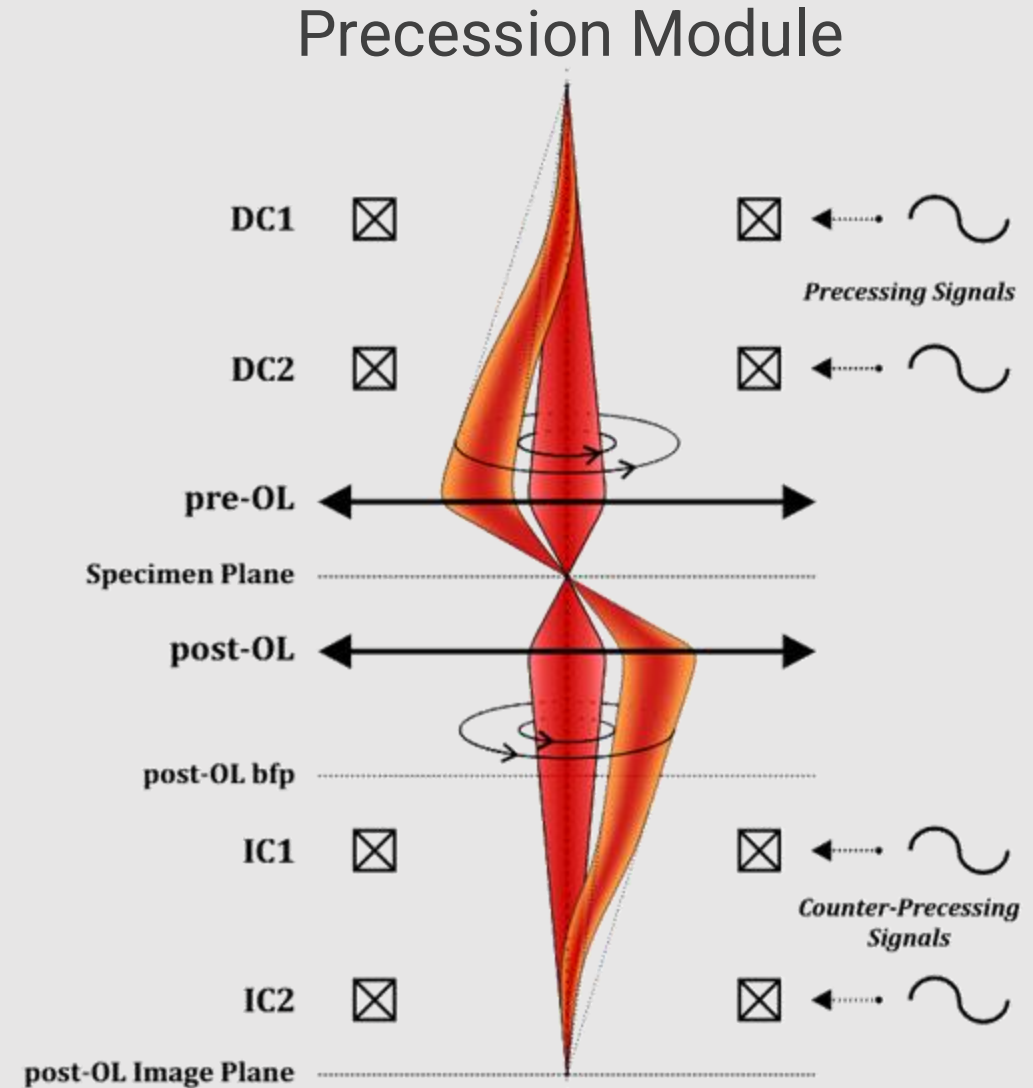
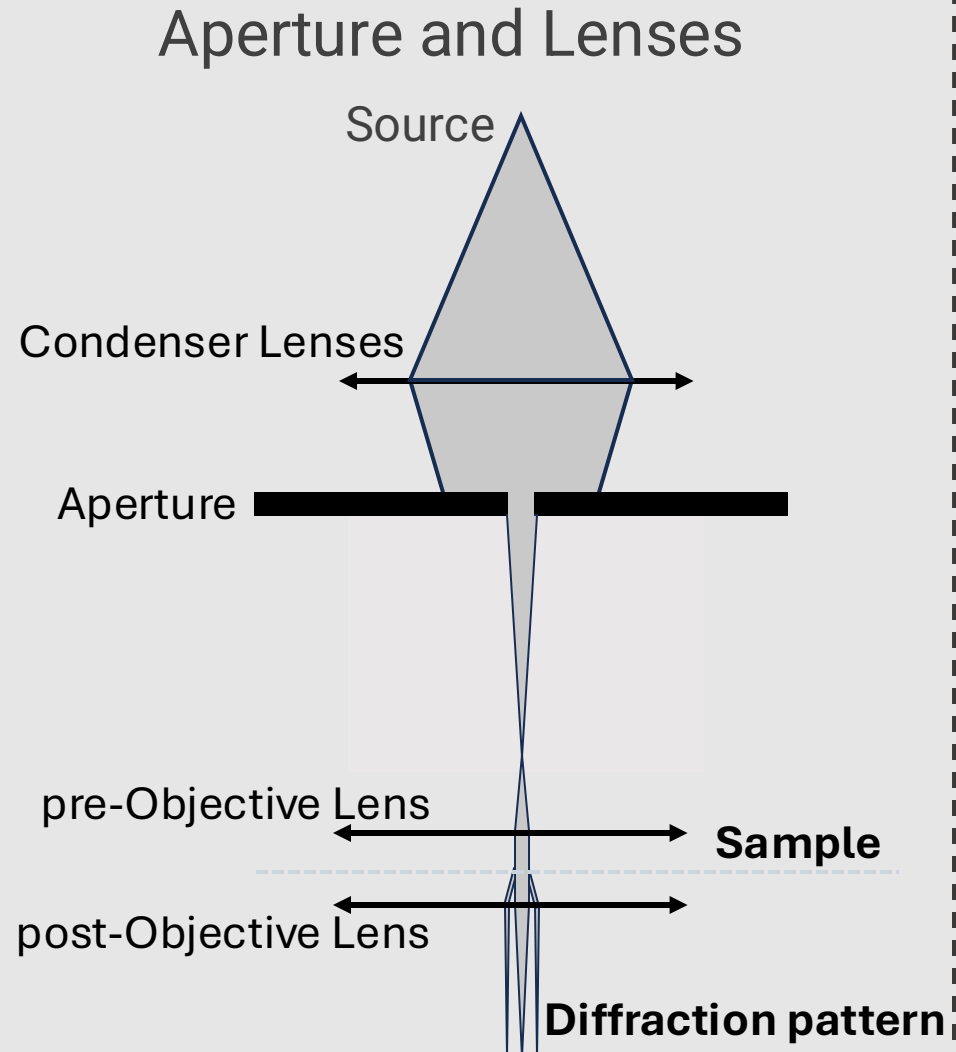
TIMEPIX

XF416

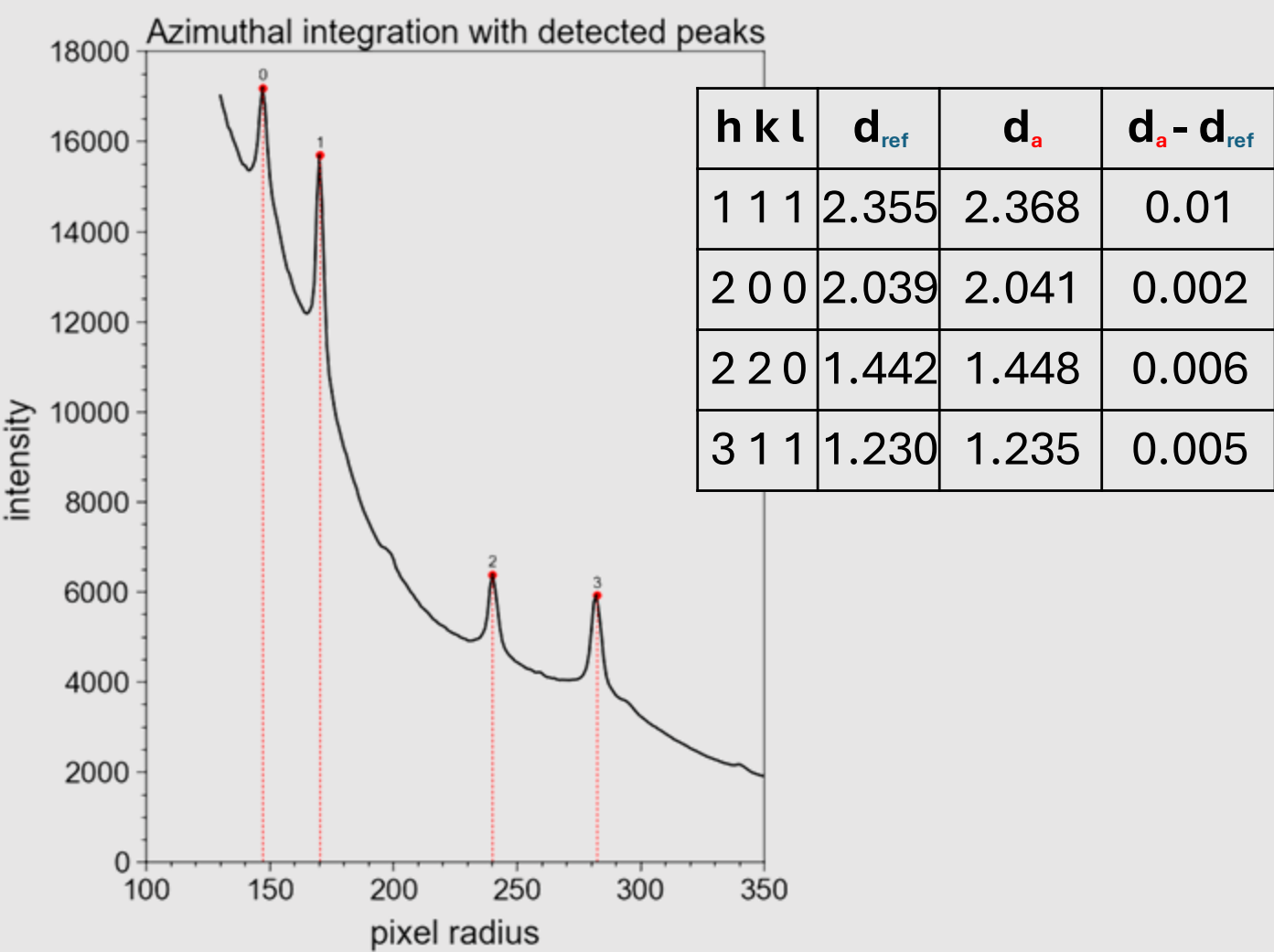
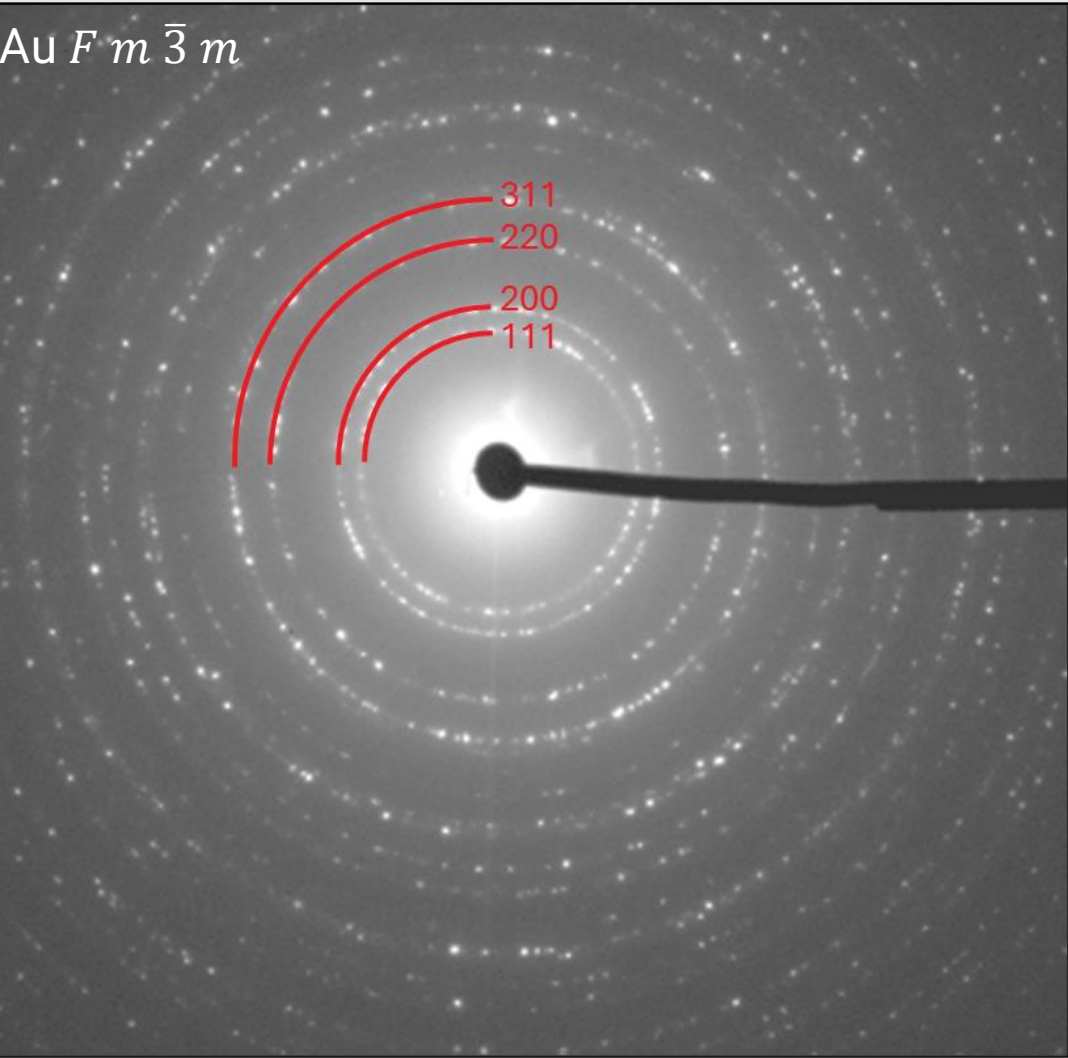
US2000



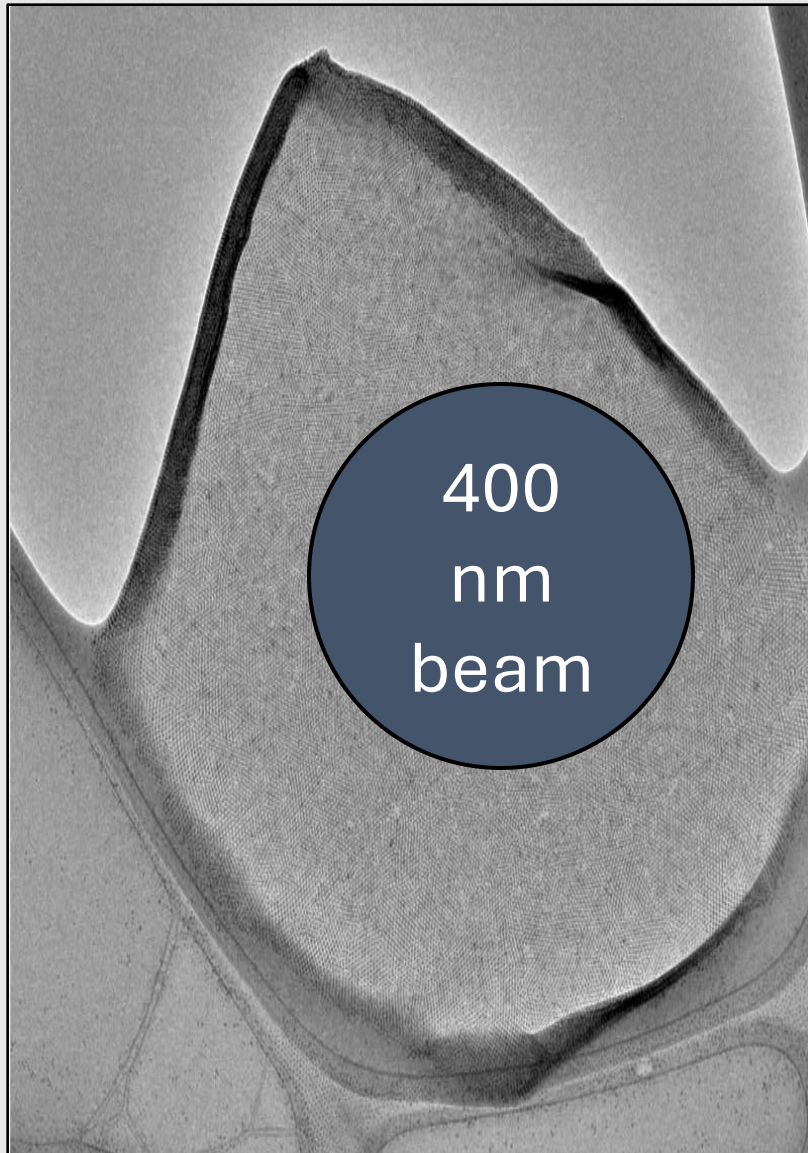
TEM Configuration



Reciprocal Space Calibration



Data Acquisition



CCD
Spot 2
7 s exposure

440
400
311
220

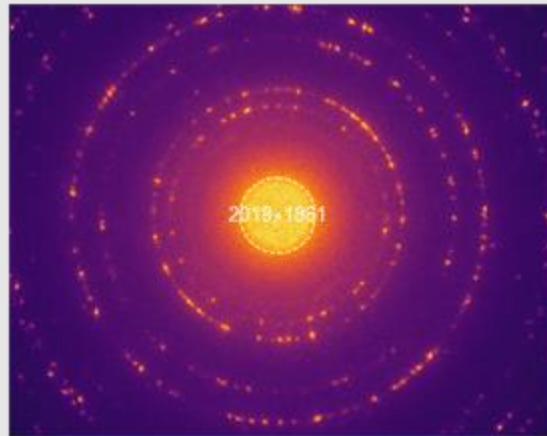
A selected area electron diffraction (SAED) pattern recorded on a CCD detector. It shows concentric white rings on a dark background. Four red curved lines are drawn over the rings, labeled with Miller indices: 440, 400, 311, and 220. A black line points from the center of the pattern to the right.

CMOS
Spot 4
1 s exposure

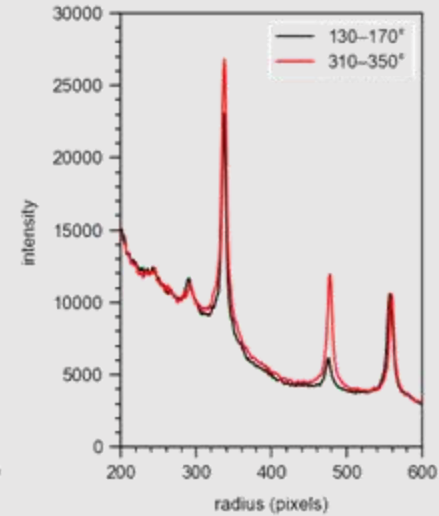
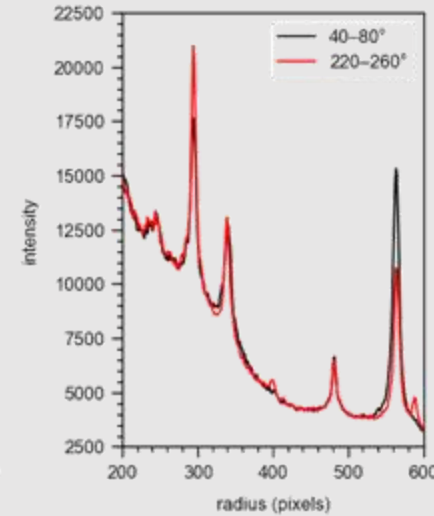
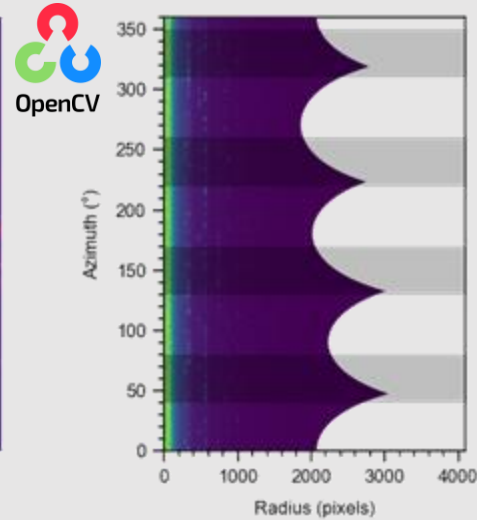
440
400
311
220

A selected area electron diffraction (SAED) pattern recorded on a CMOS detector. It shows concentric white rings on a dark background. Four red curved lines are drawn over the rings, labeled with Miller indices: 440, 400, 311, and 220. A black line points from the center of the pattern to the left.

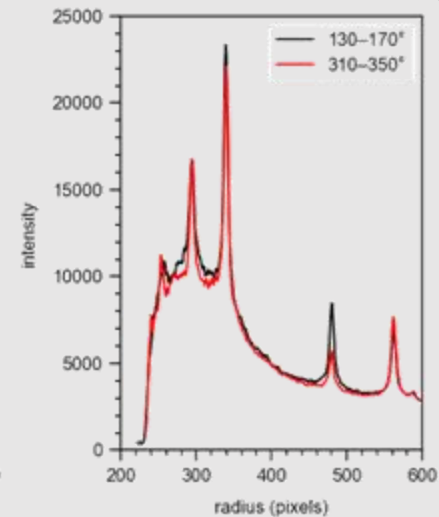
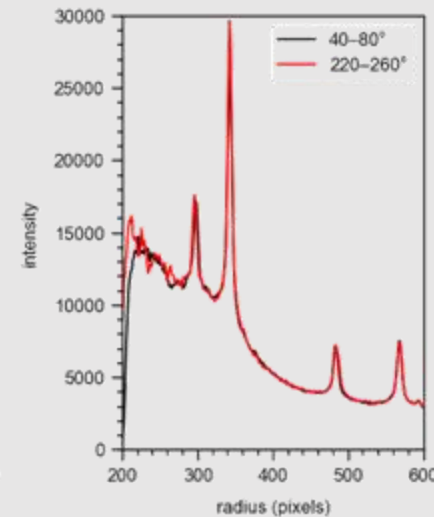
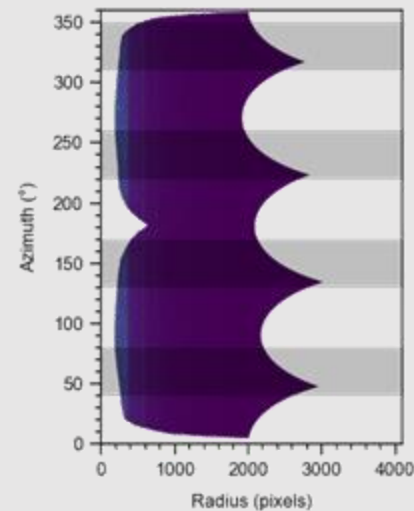
Data Processing



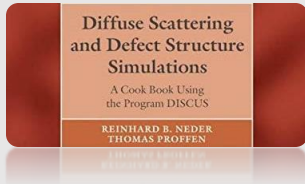
Center Finding



Beamstopper Removal

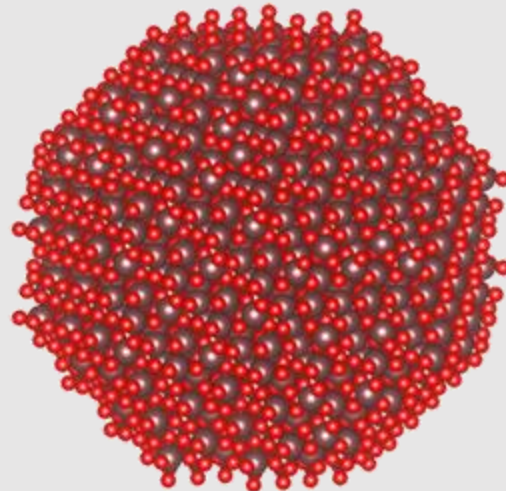
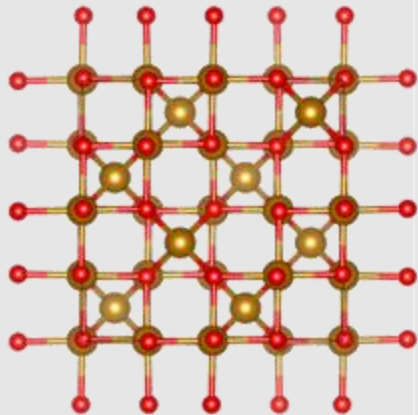


Diffraction Pattern Modelling



Spherical Particle model

Space Group : F d -3 m (Cubic Inverse Spinel)
a = 8.934 Å



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Exact and fast calculation of the X-ray pair distribution function

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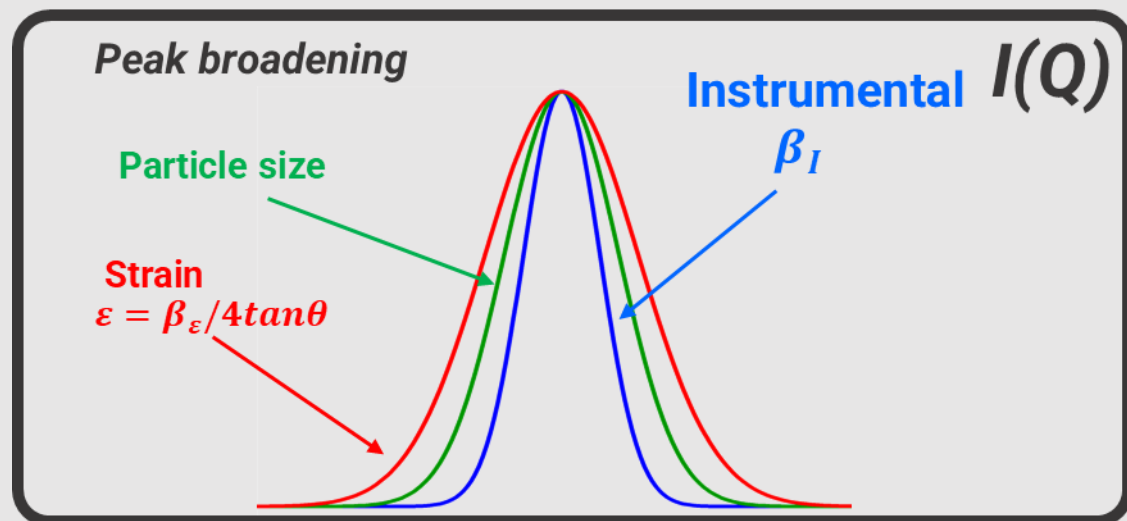
Accepted 2 April 2020

Debye Scattering Equation

$$\text{Debye}(Q) = \sum_{i=1}^N \sum_{j=1}^N f_i f_j \frac{\sin(Qr_{ij})}{Qr_{ij}}$$

Refined Parameters

Sample Contribution



Instrumental Convolution

$$PV(Q) = (1 - \eta)L + \eta G$$

$$I(Q) = \text{Debye}(Q) \otimes PV(Q)$$

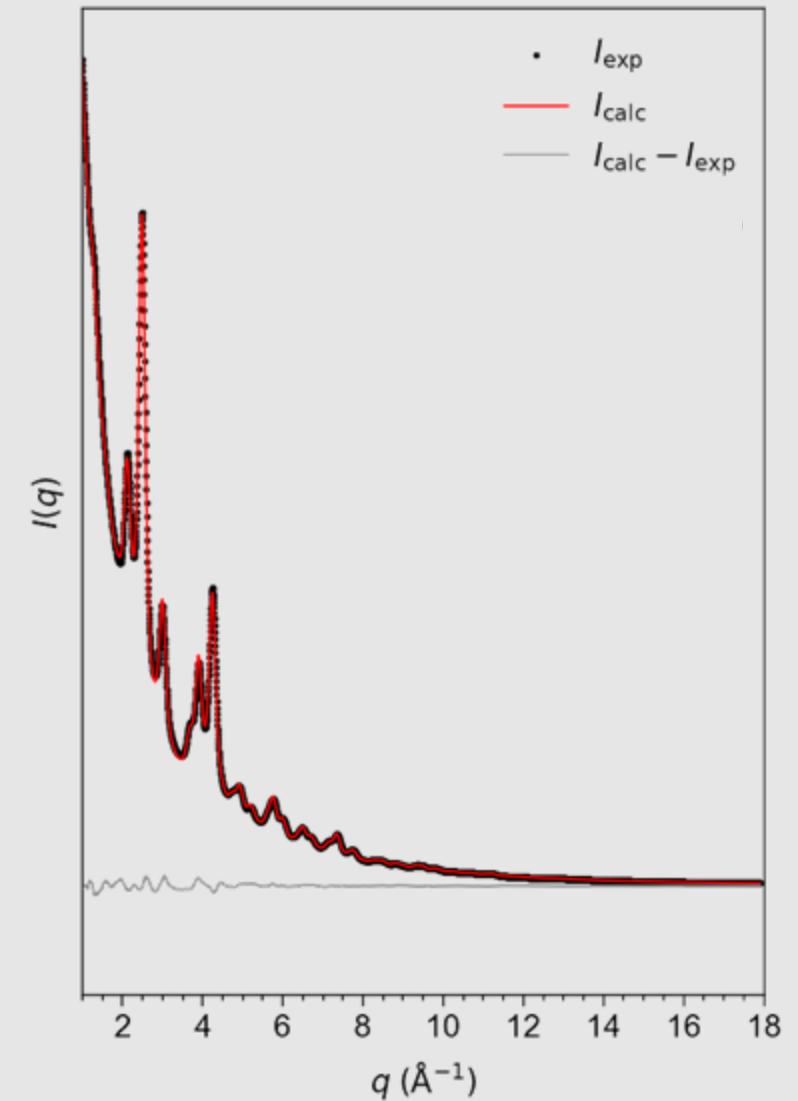
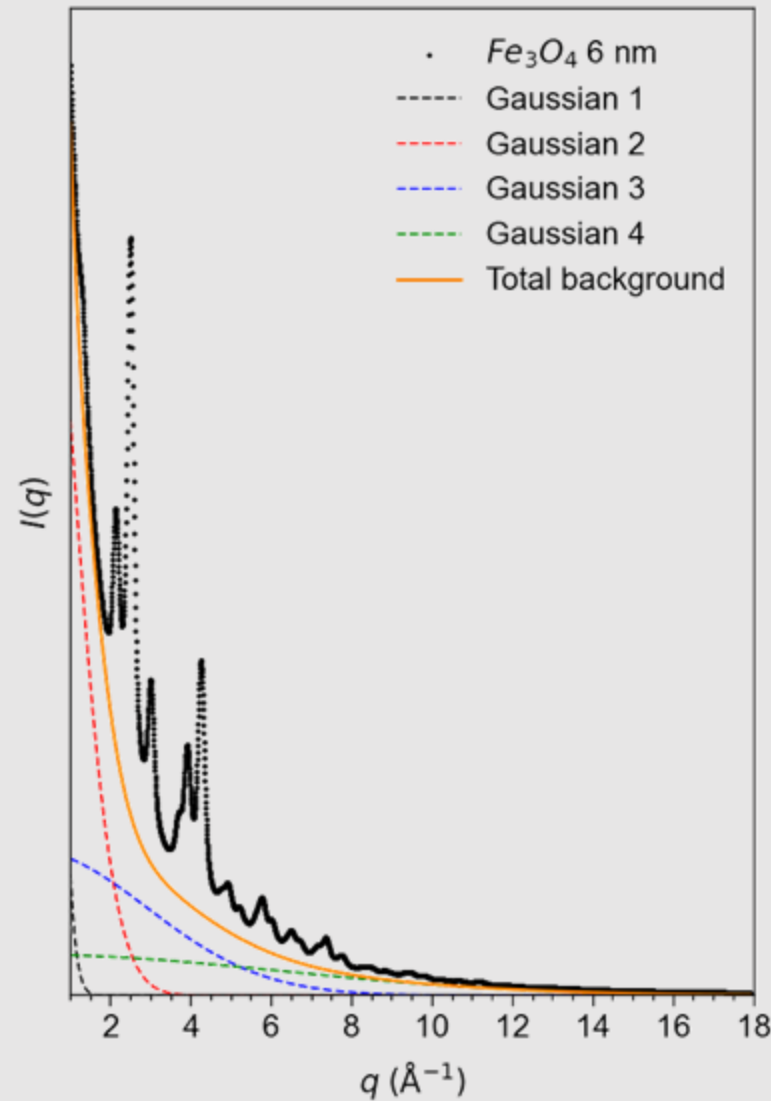
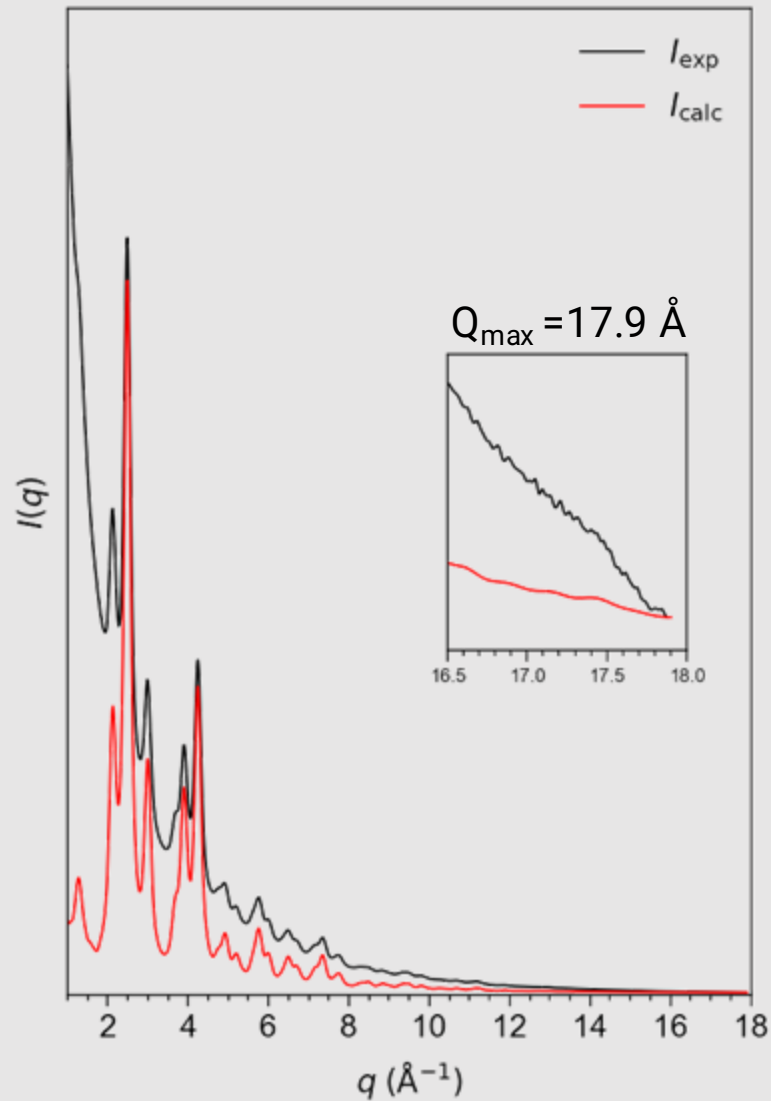
$$FWHM_Q^2 = u \cdot Q^2 + v \cdot Q + w$$

Fixed: Unit Cell Length (a), Particle Size

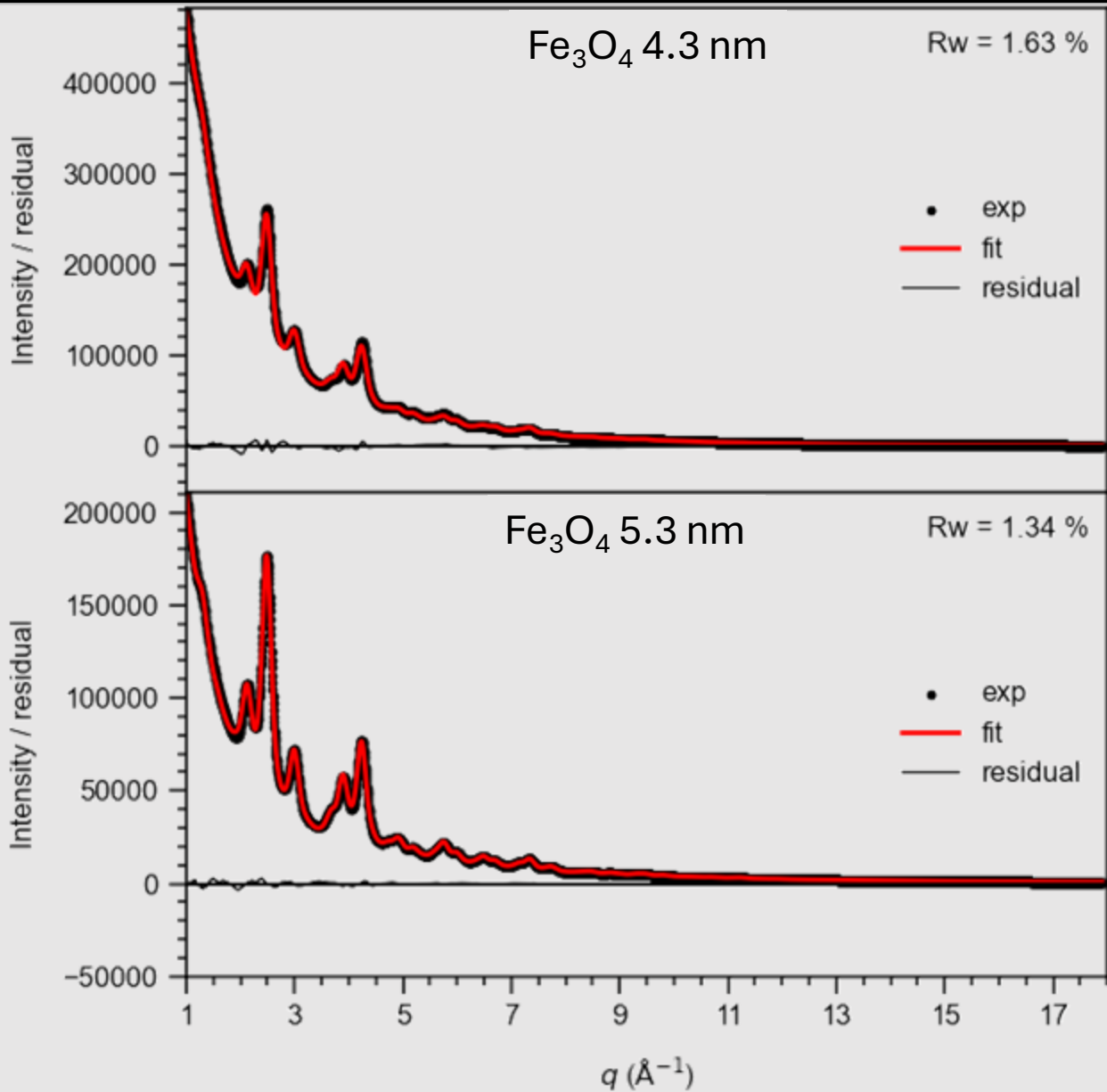
Refined: Instrument contribution (w),
Thermal parameters (B), Background,
Scale

Unaccounted: Strain

BACKGROUND MODELLING



Debye Refinement

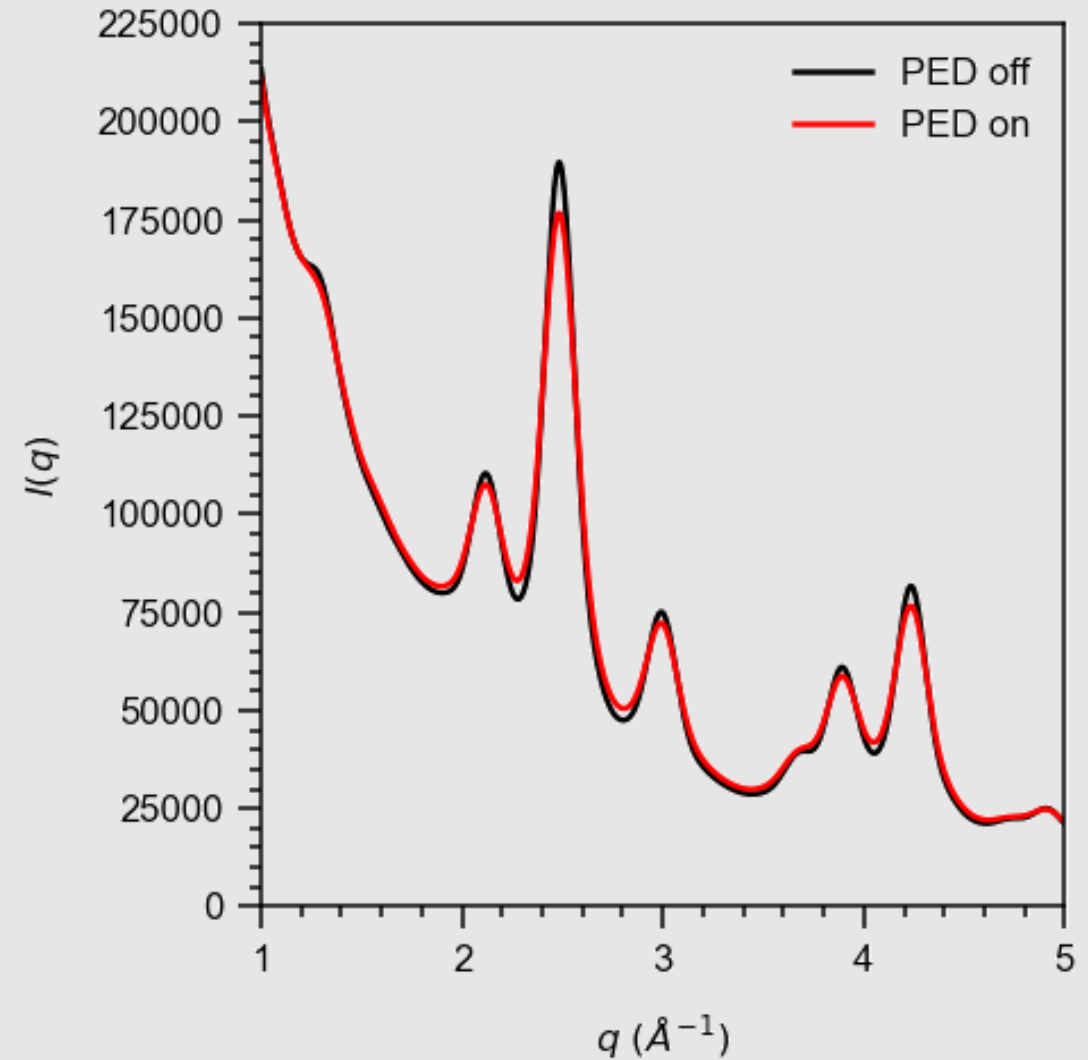
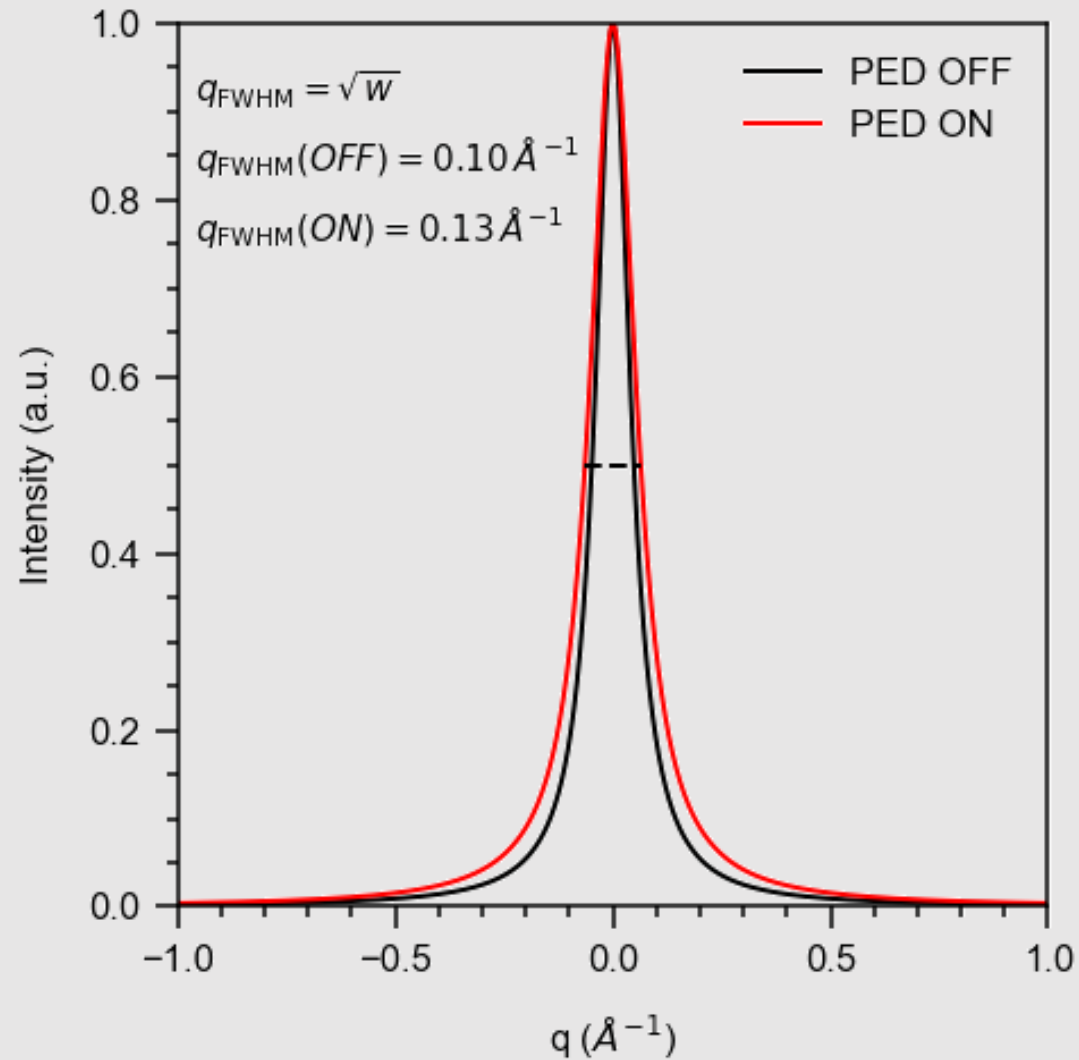


3 regions of interest (ROIs)

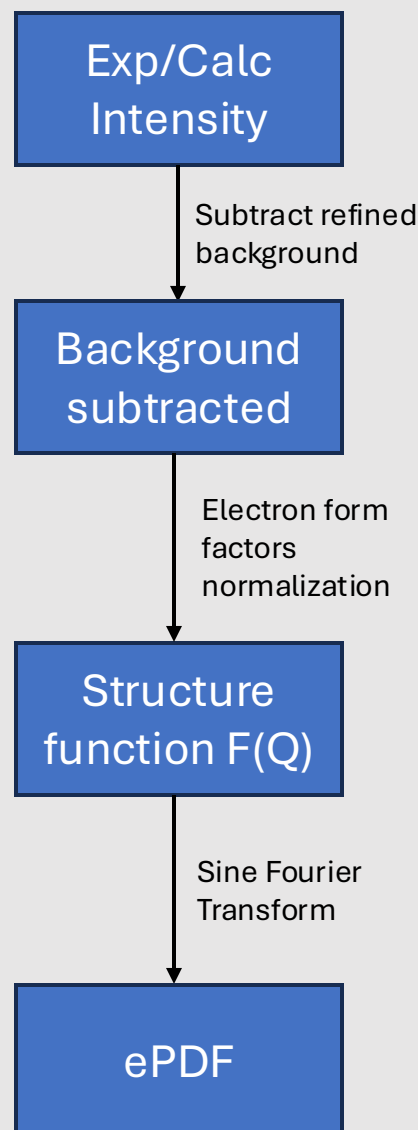
Fe ₃ O ₄ ROIs: Refined Parameters (mean ± σ)				
F30: spot 2, 400 nm beam, 380 mm KL				
Parameter	4.3 nm PED OFF	4.3 nm PED ON	5.3 nm PED OFF	5.3 nm PED ON
w (Å ⁻¹)	2e-03 ± 6e-04	3e-03 ± 2e-04	2e-03 ± 6e-04	3e-03 ± 1e-04
η	0.9999 ± 0.0002	0.99993 ± 0.00005	0.99 ± 0.02	0.96 ± 0.04
B _{metal}	1.3 ± 0.3	1.31 ± 0.05	1.0 ± 0.1	0.7 ± 0.3
B _{anions}	0.3 ± 0.1	0.31 ± 0.03	1.3 ± 0.2	1.1 ± 0.2
R _w (%)	2.8 ± 0.9	2.8 ± 0.2	1.8 ± 0.3	1.6 ± 0.2

$$FWHM_Q^2 = w$$

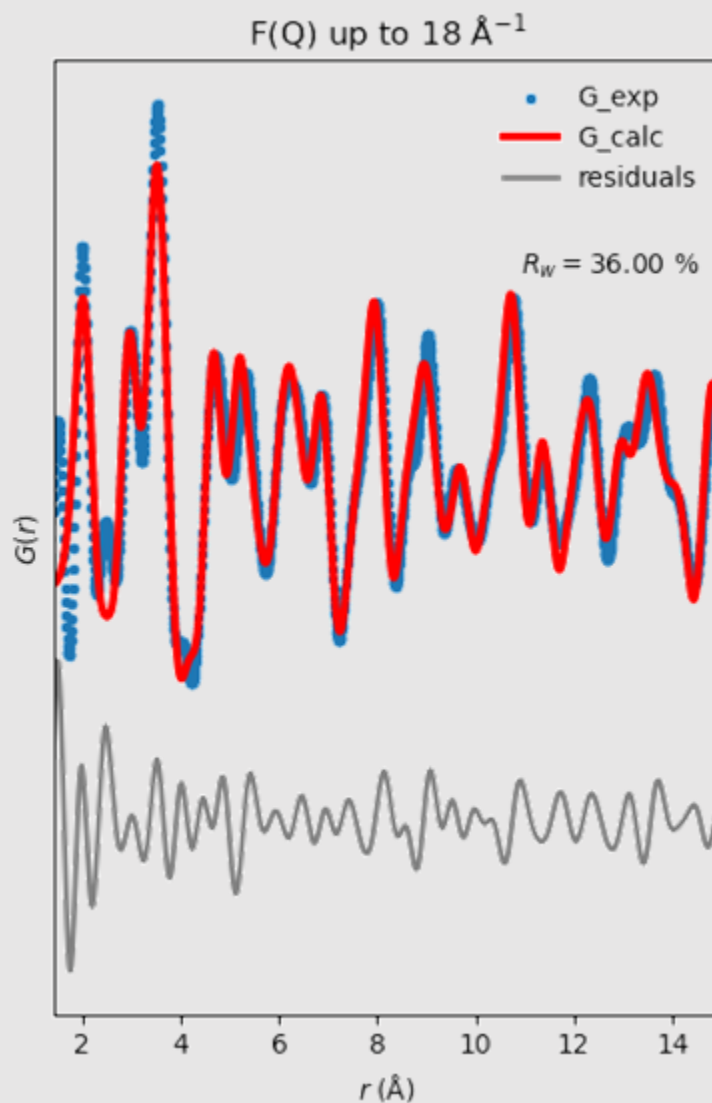
Instrument Function



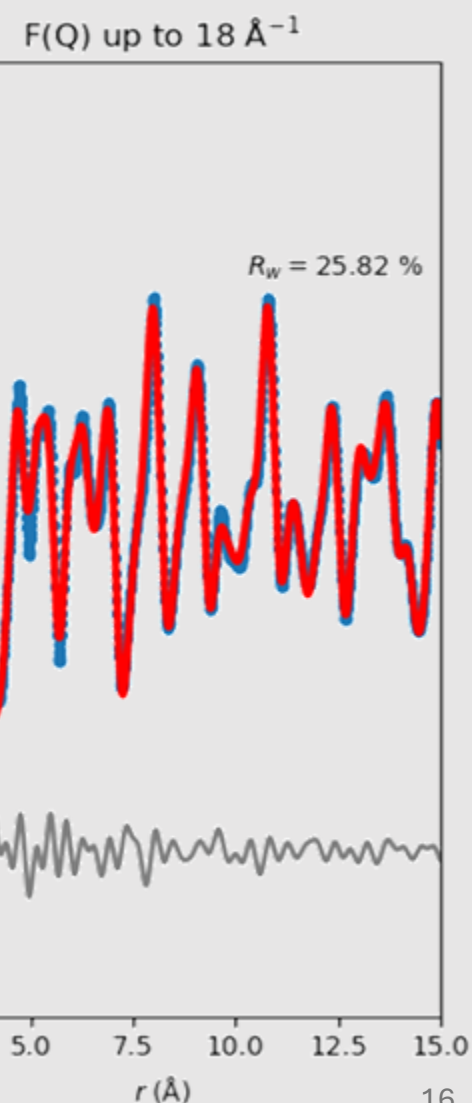
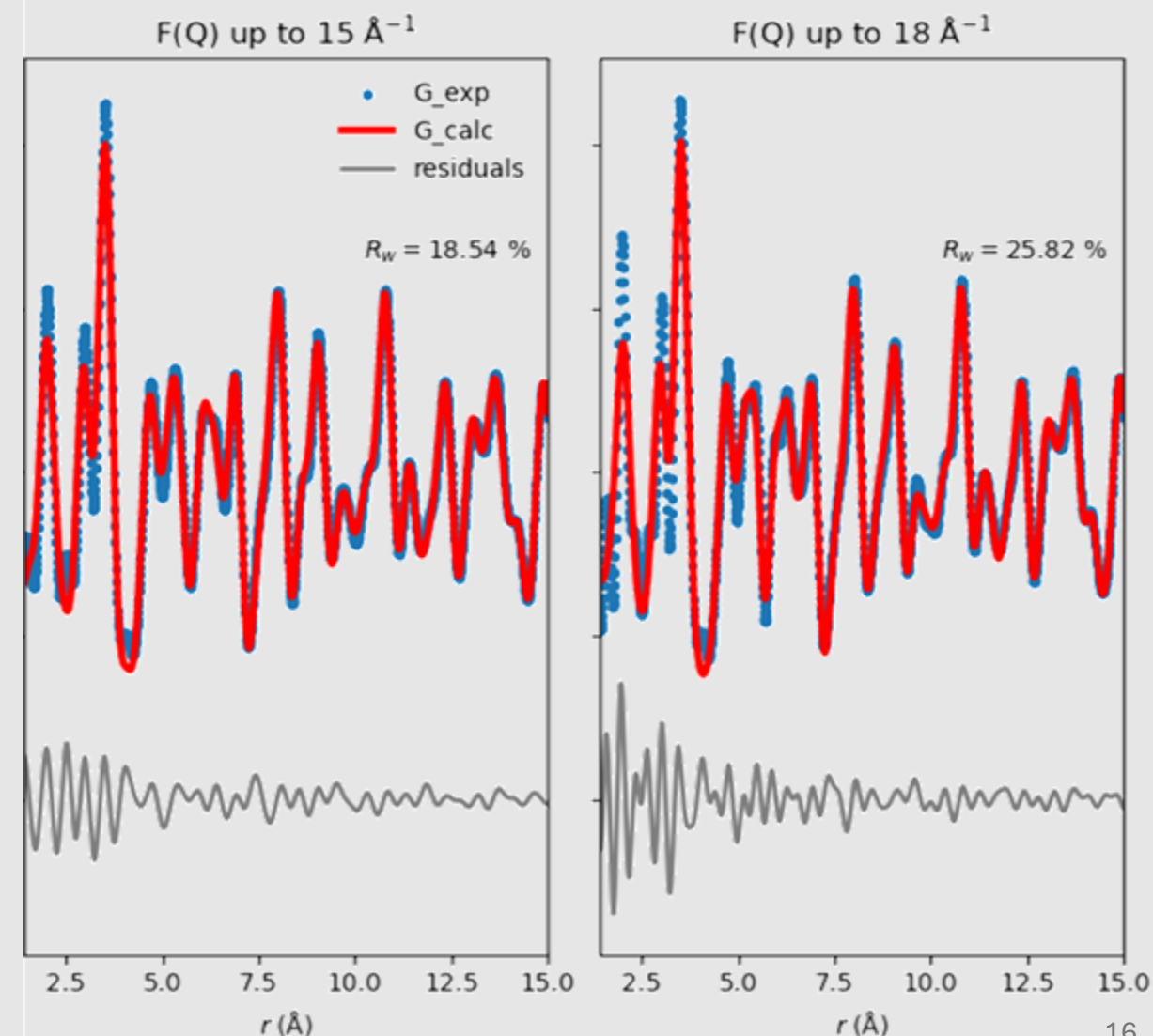
ePDF Calculation



Fe_3O_4 4.3 nm



Fe_3O_4 5.3 nm



Conclusions and Perspectives

- The crystalline particle model is a good approximation.
- Debye calculation presented good agreement for diffraction intensities.
- Lorentzian convolution approximates TEM instrument function.
- Precession alignment increases instrument FWHM but improves reproducibility.



- ☐ Unit cell and thermal parameters input from X-ray and Neutron diffraction.
- ☐ Refine instrument function for LaB_6 source and third particle size.
- ☐ Improve model with ligand simulation.
- ☐ Isolate contributions of beam convergence and detector point spread function.

Acknowledgements



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PhD Student



PhD Student



Msc. Student



Undergraduate



Co-Advisor



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PhD Student



PhD Student



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Daniela Zanchet



Germany:

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Reinhard Neder
Ute Kolb

TEM Instrumental Contribution

Reciprocal space (Q)

Real Space (r)

Peak broadening

Particle size

Strain
 $\varepsilon = \beta_\varepsilon / 4 \tan \theta$

Instrumental

β_I

$I(Q)$

FT

iFT

$G(r)$ Damping

$G(r)$

$$B(r) = e^{-\frac{(r Q_{damp})^2}{2}}$$

1.0

0.8

0.6

0.4

0.2

0.0

Q_{damp}

Crystallite

Strain

r

Diffraction damping at High-Q

Displacement factors (B, ADP)

Electron f^2

Diffuse Thermal Scattering

Detector Noise

1.0

0.8

0.6

0.4

0.2

0.0

$f_e^2 > f_e^2 > f_e^2$

Q_{max}

Q

FT

iFT

$G(r)$ peak broadening

ADP

σ'_{ij}

Correlated
motion

$\frac{\gamma}{r_{ij}} / \frac{\delta}{r_{ij}^2}$

Instrumental

Q_{Broad}

$$\sigma_{ij} = \sqrt{\sigma'_{ij} - \frac{\gamma}{r_{ij}} - \frac{\delta}{r_{ij}^2} + Q_{broad}^2 r_{ij}^2}$$



Fe_3O_4



PbS



In_2O_3



MnO

